Jun-Bo Yoon

List of Publications by Year in Descending Order

165 papers	3,275 citations	31 h-index	51 g-index
198 ext. papers	3,838 ext. citations	5.7 avg, IF	5.09 L-index

#	Paper	IF	Citations
165	Aligned CuO nanowire array for a high performance visible light photodetector.. *Scientific Reports*, **2022**, 12, 2284	4.9	1
164	Electro-Thermally Actuated Non-Volatile Mechanical Memory With CMOS-Level Operation Voltage and Low Contact Resistance. *Journal of Microelectromechanical Systems*, **2022**, 31, 87-96	2.5	0
163	Integration of Gold Nanoparticle-Carbon Nanotube Composite for Enhanced Contact Lifetime of Microelectromechanical Switches with Very Low Contact Resistance. *ACS Applied Materials & Interfaces*, **2021**, 13, 16959-16967	9.5	0
162	A review of geometric and structural design for reliable flexible electronics. *Journal of Micromechanics and Microengineering*, **2021**, 31, 074001	2	5
161	Utilizing mechanical adhesion force as a high contact force in a MEMS relay. *Sensors and Actuators A: Physical*, **2021**, 331, 112894	3.9	4
160	Geometrically Structured Nanomaterials for Nanosensors, NEMS, and Nanosieves. *Advanced Materials*, **2020**, 32, e1907082	24	10
159	Realization of Nanolene: A Planar Array of Perfectly Aligned, Air-Suspended Nanowires. *Small*, **2020**, 16, e1906845	11	4
158	Ultra-Sensitive Strain Sensor Using High Density Self-Aligned Nano-Cracks **2020**,		2
157	Nanowires: Realization of Nanolene: A Planar Array of Perfectly Aligned, Air-Suspended Nanowires (Small 13/2020). *Small*, **2020**, 16, 2070072	11	
156	Always-On Gas Sensors: Perfectly Aligned, Air-Suspended Nanowire Array Heater and Its Application in an Always-On Gas Sensor (Adv. Funct. Mater. 39/2020). *Advanced Functional Materials*, **2020**, 30, 2070264	15.6	1
155	Chemo-Mechanically Operating Palladium-Polymer Nanograting Film for a Self-Powered H Gas Sensor. *ACS Nano*, **2020**,	16.7	9
154	4 W Power MEMS Relay With Extremely Low Contact Resistance: Theoretical Analysis, Design and Demonstration. *Journal of Microelectromechanical Systems*, **2020**, 29, 1304-1313	2.5	2
153	Perfectly Aligned, Air-Suspended Nanowire Array Heater and Its Application in an Always-On Gas Sensor. *Advanced Functional Materials*, **2020**, 30, 2004448	15.6	5
152	4 W Dual-Contact Material MEMS Relay with a Contact Force Maximizing Structure **2020**,		1
151	Self-Powered, Ultra-Reliable Hydrogen Sensor Exploiting Chemomechanical Nano-Transducer and Solar-Cell **2019**,		1
150	High-Performance Copper Oxide Visible-Light Photodetector via Grain-Structure Model. *Scientific Reports*, **2019**, 9, 7334	4.9	28
149	Integration of a Carbon Nanotube Network on a Microelectromechanical Switch for Ultralong Contact Lifetime. *ACS Applied Materials & Interfaces*, **2019**, 11, 18617-18625	9.5	5

148	Batch-fabricated CO gas sensor in large-area (8-inch) with sub-10 mW power operation. *Sensors and Actuators B: Chemical*, **2019**, 289, 153-159	8.5	14
147	Stress-engineered palladium nanowires for wide range (0.1%-3.9%) of H detection with high durability. *Nanoscale*, **2019**, 11, 16317-16326	7.7	12
146	An investigation of surficial conduction heat loss in perfectly aligned micro-wire array. *Applied Physics Letters*, **2019**, 115, 131901	3.4	2
145	**2019**,		1
144	Mass-producible structural design and fabrication method for a slim light-guide plate having inverse-trapezoidal light out-couplers. *Journal of Micromechanics and Microengineering*, **2019**, 29, 035001	2	1
143	>1000-Fold Lifetime Extension of a Nickel Electromechanical Contact Device via Graphene. *ACS Applied Materials & Interfaces*, **2018**, 10, 9085-9093	9.5	17
142	A Low Contact Resistance 4-Terminal Mems Relay: Theoretical Analysis, Design, and Demonstration. *Journal of Microelectromechanical Systems*, **2018**, 27, 497-505	2.5	6
141	Material-Independent Nanotransfer onto a Flexible Substrate Using Mechanical-Interlocking Structure. *ACS Nano*, **2018**, 12, 4387-4397	16.7	17
140	First Lateral Contact Probing of 55- mu m Fine Pitch Micro-Bumps. *Journal of Microelectromechanical Systems*, **2018**, 27, 1114-1123	2.5	3
139	A Proactive Plastic Deformation Method for Fine-Tuning of Metal-Based MEMS Devices After Fabrication. *Journal of Microelectromechanical Systems*, **2018**, 27, 1124-1134	2.5	1
138	Touch Sensors: Industrial Grade, Bending-Insensitive, Transparent Nanoforce Touch Sensor via Enhanced Percolation Effect in a Hierarchical Nanocomposite Film (Adv. Funct. Mater. 42/2018). *Advanced Functional Materials*, **2018**, 28, 1870305	15.6	
137	Edge-lit LCD backlight unit for 2D local dimming. *Optics Express*, **2018**, 26, 20802-20812	3.3	14
136	Industrial Grade, Bending-Insensitive, Transparent Nanoforce Touch Sensor via Enhanced Percolation Effect in a Hierarchical Nanocomposite Film. *Advanced Functional Materials*, **2018**, 28, 1804721	15.6	35
135	Versatile Transfer of an Ultralong and Seamless Nanowire Array Crystallized at High Temperature for Use in High-Performance Flexible Devices. *ACS Nano*, **2017**, 11, 1520-1529	16.7	41
134	Carbon nanotubes network contact lubrication for highly reliable MEMS switch **2017**,		2
133	Highly aligned suspended nanowire array for self-heating type gas sensors **2017**,		2
132	Performance-enhanced triboelectric nanogenerator enabled by wafer-scale nanograte of multistep pattern downscaling. *Nano Energy*, **2017**, 35, 415-423	17.1	101
131	Realization of large-scale sub-10□hm nanogratings using a repetitive wet-chemical oxidation and etching technique. *Micro and Nano Systems Letters*, **2017**, 5,	2	2

130	Nanomechanical Encoding Method Using Enhanced Thermal Concentration on a Metallic Nanobridge. *ACS Nano*, **2017**, 11, 7781-7789	16.7	7
129	Efforts toward ideal microelectromechanical switches **2017**,		1
128	Nanotransplantation Printing of Crystallographic-Orientation-Controlled Single-Crystalline Nanowire Arrays on Diverse Surfaces. *ACS Nano*, **2017**, 11, 11642-11652	16.7	12
127	. *Journal of Microelectromechanical Systems*, **2017**, 26, 1417-1427	2.5	4
126	4-Terminal MEMS relay with an extremely low contact resistance employing a novel one-contact design **2017**,		2
125	Micro and Nanoelectromechanical Contact Switches for Logic, Memory, and Power Applications. *KAIST Research Series*, **2016**, 65-117		1
124	. *Journal of Microelectromechanical Systems*, **2016**, 25, 909-915	2.5	
123	A Highly Reliable MEMS Relay With Two-Step Spring System and Heat Sink Insulator for High-Power Switching Applications. *Journal of Microelectromechanical Systems*, **2016**, 25, 217-226	2.5	14
122	P-67: Wide Bandwidth Reflective Microshutter Blind Panel for Transparent Organic Light-Emitting Diode Display. *Digest of Technical Papers SID International Symposium*, **2016**, 47, 1389-1391	0.5	1
121	P-70: Light Shifted Light-guide Plate for Simple Multi-view Spatial/Temporal Hybrid Autostereoscopic Display. *Digest of Technical Papers SID International Symposium*, **2016**, 47, 1399-1401	0.5	1
120	P-72: Ultra-thin Edge Type Single Sheet Backlight Unit for Seamless Two-dimensional Local Dimming. *Digest of Technical Papers SID International Symposium*, **2016**, 47, 1406-1408	0.5	4
119	Unconventional Use of a Photoresist as a Nitrogen Gas Generator Forming Transparent Dome-Shaped Microcavities . *Advanced Engineering Materials*, **2016**, 18, 559-566	3.5	2
118	. *Journal of Microelectromechanical Systems*, **2015**, 24, 1495-1502	2.5	13
117	Increasing Capacitance and Self-Resonant Frequency of the MEMS Switched Capacitor Using High-$kappa $ TiO2 and SU-8 Bridged Beam Structure. *Journal of Microelectromechanical Systems*, **2015**, 24, 1006-1015	2.5	3
116	Highly reliable MEMS relay with two-step spring system and heat sink insulator for power applications **2015**,		5
115	Effect of excitation point on surface phonon fields in phononic crystals in real- and k-space. *Journal of Applied Physics*, **2015**, 117, 245308	2.5	3
114	A simple breathing rate-sensing method exploiting a temporarily condensed water layer formed on an oxidized surface. *Applied Physics Letters*, **2015**, 106, 053701	3.4	22
113	. *Journal of Microelectromechanical Systems*, **2015**, 24, 1545-1556	2.5	4

112	High-performance hybrid complementary logic inverter through monolithic integration of a MEMS switch and an oxide TFT. *Small*, **2015**, 11, 1390-5	11	10
111	Fabrication of a membrane filter with controlled pore shape and its application to cell separation and strong single cell trapping. *Journal of Micromechanics and Microengineering*, **2015**, 25, 105007	2	9
110	Self-cleaning hybrid energy harvester to generate power from raindrop and sunlight. *Nano Energy*, **2015**, 12, 636-645	17.1	118
109	A mechanical and electrical transistor structure (METS) with a sub-2 nm nanogap for effective voltage scaling. *Nanoscale*, **2014**, 6, 7799-804	7.7	12
108	A Complementary Dual-Contact MEMS Switch Using a Zipping Technique. *Journal of Microelectromechanical Systems*, **2014**, 23, 710-718	2.5	20
107	Ultra-low voltage MEMS switch using a folded hinge structure. *Micro and Nano Systems Letters*, **2014**, 2,	2	10
106	Electrostatic micro-actuator with a pre-charged series capacitor: modeling, design, and demonstration. *Journal of Micromechanics and Microengineering*, **2014**, 24, 065012	2	10
105	Novel buried inverse-trapezoidal micropattern for dual-sided light extracting backlight unit. *Optics Express*, **2014**, 22, 32440-9	3.3	4
104	Three-dimensional (3-D) reshaping technique in MEMS devices by solely electrical control with ultrafine tuning resolution **2014**,		1
103	Voltage-Controlled $C{-}V$ Response Tuning in a Parallel Plate MEMS Variable Capacitor. *Journal of Microelectromechanical Systems*, **2013**, 22, 1403-1413	2.5	4
102	Complementary Dual-Contact Switch Using Soft and Hard Contact Materials for Achieving Low Contact Resistance and High Reliability Simultaneously. *Journal of Microelectromechanical Systems*, **2013**, 22, 846-854	2.5	20
101	A new approach to control a deflection of an electroplated microstructure: dual current electroplating methods. *Journal of Micromechanics and Microengineering*, **2013**, 23, 055016	2	7
100	High throughput ultralong (20 cm) nanowire fabrication using a wafer-scale nanograting template. *Nano Letters*, **2013**, 13, 3978-84	11.5	33
99	A sub-1-volt nanoelectromechanical switching device. *Nature Nanotechnology*, **2013**, 8, 36-40	28.7	135
98	Actively transparent display with enhanced legibility based on an organic light-emitting diode and a cholesteric liquid crystal blind panel. *Optics Express*, **2013**, 21, 10358-66	3.3	15
97	Improvement of hot switching lifetime in MEMS DC switches using a drain voltage-sustaining capacitor **2013**,		3
96	An ultra-low voltage MEMS switch using stiction-recovery actuation. *Journal of Micromechanics and Microengineering*, **2013**, 23, 045022	2	19
95	A CMOS label-free DNA sensor using electrostatic induction of molecular charges. *Biosensors and Bioelectronics*, **2012**, 31, 343-8	11.8	22

94	An Electrostatically Actuated Stacked-Electrode MEMS Relay With a Levering and Torsional Spring for Power Applications. *Journal of Microelectromechanical Systems*, **2012**, 21, 1209-1217	2.5	28
93	Fabrication of a uniform microlens array over a large area using self-aligned diffuser lithography (SADL). *Journal of Micromechanics and Microengineering*, **2012**, 22, 045002	2	16
92	An effective light-extracting microstructure for a single-sheet backlight unit for liquid crystal display. *Journal of Micromechanics and Microengineering*, **2012**, 22, 095006	2	9
91	High-performance MEMS relay using a stacked-electrode structure and a levering and torsional spring for power applications **2012**,		2
90	An electrostatic micromechanical biosensor for electrical detection of label-free DNA. *Applied Physics Letters*, **2012**, 100, 163701	3.4	6
89	CMOS capacitive biosensor with enhanced sensitivity for label-free DNA detection **2012**,		19
88	Use of a columnar metal thin film as a nanosieve with sub-10 nm pores. *Advanced Materials*, **2012**, 24, 4408-13	24	19
87	Transparent conducting hybrid thin films fabricated by layer-by-layer assembly of single-wall carbon nanotubes and conducting polymers. *Applied Physics A: Materials Science and Processing*, **2012**, 108, 305-311	2.6	11
86	Multi-resonant energy harvester exploiting high-mode resonances frequency down-shifted by a flexible body beam. *Applied Physics Letters*, **2012**, 101, 123903	3.4	14
85	Metal-oxide-semiconductor field effect transistor humidity sensor using surface conductance. *Applied Physics Letters*, **2012**, 100, 101603	3.4	35
84	Adhesion Force Change by Electrowetting on a Polymer Microlens Array. *Journal of Adhesion Science and Technology*, **2012**, 26, 2079-2086	2	6
83	MEMS variable capacitor with superior linearity and large tuning ratio by moving the plate to the increasing-gap direction **2011**,		4
82	Parallel-Plate MEMS Variable Capacitor With Superior Linearity and Large Tuning Ratio Using a Levering Structure. *Journal of Microelectromechanical Systems*, **2011**, 20, 1345-1354	2.5	24
81	Fast and robust cantilever switch with suppressed bouncing for ic applications **2011**,		1
80	An insulating liquid environment for reducing adhesion in a microelectromechanical system. *Applied Physics Letters*, **2011**, 99, 113516	3.4	10
79	Fabrication of a large-scale Ni stamp using a multi-level SU-8 photoresist mold for advanced printed circuit board manufacturing. *Journal of Micromechanics and Microengineering*, **2011**, 21, 065026	2	3
78	Mass-Producible Polydimethylsiloxane (PDMS) Frontlight Unit (FLU) for Reflective Displays. *Journal of Display Technology*, **2011**, 7, 526-531		3
77	An Extremely Low Contact-Resistance MEMS Relay Using Meshed Drain Structure and Soft Insulating Layer. *Journal of Microelectromechanical Systems*, **2011**, 20, 204-212	2.5	29

76	Modeling, fabrication and demonstration of a rib-type cantilever switch with an extended gate electrode. *Journal of Micromechanics and Microengineering*, **2011**, 21, 115009	2	9
75	An autonomous CMOS hysteretic sensor for the detection of desorption-free DNA hybridization. *Biosensors and Bioelectronics*, **2011**, 26, 4591-5	11.8	7
74	Liquid-based electrostatic energy harvester with high sensitivity to human physical motion. *Smart Materials and Structures*, **2011**, 20, 125012	3.4	24
73	A trans-scaled nanofabrication using 3D diffuser lithography, metal molding and nano-imprinting. *Journal of Micromechanics and Microengineering*, **2011**, 21, 045025	2	7
72	Modeling, fabrication and demonstration of an electrostatic actuator with a coplanar pre-charged electrode. *Journal of Micromechanics and Microengineering*, **2011**, 21, 085012	2	3
71	Exchangeable self-curable liquid gate dielectric embedded field effect transistor. *Applied Physics Letters*, **2010**, 97, 032112	3.4	3
70	Use of nanoporous columnar thin film in the wafer-level packaging of MEMS devices. *Journal of Micromechanics and Microengineering*, **2010**, 20, 045002	2	8
69	High performance microshutter device with space-division modulation. *Journal of Micromechanics and Microengineering*, **2010**, 20, 075030	2	6
68	Analytical modeling and thermodynamic analysis of robust superhydrophobic surfaces with inverse-trapezoidal microstructures. *Langmuir*, **2010**, 26, 17389-97	4	30
67	A robust superhydrophobic and superoleophobic surface with inverse-trapezoidal microstructures on a large transparent flexible substrate. *Soft Matter*, **2010**, 6, 1401	3.6	290
66	Electrowetting on a polymer microlens array. *Langmuir*, **2010**, 26, 12443-7	4	32
65	Mechanical Reliability of a Digital Micromirror With Interdigitated Cantilevers. *Journal of Microelectromechanical Systems*, **2010**, 19, 1197-1206	2.5	5
64	56.2: A New Reflective-type Transparent Display Using Cholesteric Liquid Crystal. *Digest of Technical Papers SID International Symposium*, **2010**, 41, 838	0.5	6
63	Optically selective microlens photomasks using self-assembled smectic liquid crystal defect arrays. *Advanced Materials*, **2010**, 22, 2416-20	24	44
62	One-chip electronic detection of DNA hybridization using precision impedance-based CMOS array sensor. *Biosensors and Bioelectronics*, **2010**, 26, 1373-9	11.8	30
61	Nanowire mechanical switch with a built-in diode. *Small*, **2010**, 6, 1197-200	11	18
60	Densely-Packed Microbowl Array with Balanced Dielectrophoretic Forces for Single-Cell Microarray. *Materials Research Society Symposia Proceedings*, **2009**, 1222, 1		
59	Spontaneous Lamellar Alignment in Thickness-Modulated Block Copolymer Films. *Advanced Functional Materials*, **2009**, 19, 2584-2591	15.6	59

58	"Lock-and-key" geometry effect of patterned surfaces: wettability and switching of adhesive force. *Small*, **2009**, 5, 90-4	11	97
57	Modeling, Design, Fabrication, and Demonstration of a Digital Micromirror With Interdigitated Cantilevers. *Journal of Microelectromechanical Systems*, **2009**, 18, 1382-1395	2.5	10
56	MEMS-Based Tunable LC Bandstop Filter With an Ultra-Wide Continuous Tuning Range. *IEEE Microwave and Wireless Components Letters*, **2009**, 19, 710-712	2.6	25
55	Linearly variable inductor with RF MEMS switches to enlarge a continuous tuning range **2009**,		3
54	A conventional route to scalable morphology-controlled regular structures and their superhydrophobic/hydrophilic properties for biochips application. *Lab on A Chip*, **2009**, 9, 2140-4	7.2	28
53	3-terminal nanoelectromechanical switching device in insulating liquid media for low voltage operation and reliability improvement **2009**,		22
52	Indium Tin Oxide (ITO) Transparent MEMS Switches **2009**,		5
51	A Highly Flexible Superhydrophobic Microlens Array with Small Contact Angle Hysteresis for Droplet-Based Microfluidics **2009**,		2
50	Nanoelectromechanical (NEM) relays integrated with CMOS SRAM for improved stability and low leakage **2009**,		43
49	Mechanically Operated Random Access Memory (MORAM) Based on an Electrostatic Microswitch for Nonvolatile Memory Applications. *IEEE Transactions on Electron Devices*, **2008**, 55, 2785-2789	2.9	18
48	High-Q, tunable-gap MEMS variable capacitor actuated with an electrically floating plate **2008**,		4
47	Silicon Photonic Wire Filter Using Asymmetric Sidewall Long-Period Waveguide Grating in a Two-Mode Waveguide. *IEEE Photonics Technology Letters*, **2008**, 20, 520-522	2.2	15
46	Fabrication and characterization of a nanoelectromechanical switch with 15-nm-thick suspension air gap. *Applied Physics Letters*, **2008**, 92, 103110	3.4	112
45	A simple and effective fabrication method for various 3D microstructures: backside 3D diffuser lithography. *Journal of Micromechanics and Microengineering*, **2008**, 18, 125015	2	44
44	3.4: Invited Paper: A Novel Use of MEMS Switches in Driving AMOLED. *Digest of Technical Papers SID International Symposium*, **2008**, 39, 13	0.5	1
43	A one-step route to a perfectly ordered wafer-scale microbowl array for size-dependent superhydrophobicity. *Small*, **2008**, 4, 211-6	11	37
42	NEMS switch with 30 nm-thick beam and 20 nm-thick air-gap for high density non-volatile memory applications. *Solid-State Electronics*, **2008**, 52, 1578-1583	1.7	74
41	Sloping profile and pattern transfer to silicon by shape-controllable 3-D lithography and ICP. *Sensors and Actuators A: Physical*, **2007**, 139, 281-286	3.9	6

40	A Dram-Like Mechanical Non-Volatile Memory **2007**,		6
39	P-73: A Novel LCD Backlight Unit using a Light-guide Plate with High Fill-factor Microlens Array and a Conical Microlens Array Sheet. *Digest of Technical Papers SID International Symposium*, **2007**, 38, 465-468	0.5	5
38	Simple liquid crystal display backlight unit comprising only a single-sheet micropatterned polydimethylsiloxane (PDMS) light-guide plate. *Optics Letters*, **2007**, 32, 2665-7	3	61
37	MEMS Variable Capacitor Actuated with an Electrically Floating Plate **2007**,		7
36	Fabrication of three-dimensional SiC-based ceramic micropatterns using a sequential micromolding-and-pyrolysis process. *Microelectronic Engineering*, **2006**, 83, 2475-2481	2.5	12
35	A 3-D planar microlens for an effective monolithic optical interconnection system. *IEEE Photonics Technology Letters*, **2006**, 18, 814-816	2.2	9
34	Microlens array diffuser for a light-emitting diode backlight system. *Optics Letters*, **2006**, 31, 3016-8	3	126
33	Micromachined CPW-fed suspended patch antenna for 77 GHz automotive radar applications **2005**,		1
32	A simple and effective lift-off with positive photoresist. *Journal of Micromechanics and Microengineering*, **2005**, 15, 2136-2140	2	60
31	60-GHz CPW-fed post-supported patch antenna using micromachining technology. *IEEE Microwave and Wireless Components Letters*, **2005**, 15, 635-637	2.6	54
30	Self-assembled monolayer-assisted thin metal polishing for fabricating uniform 3D microstructures. *Journal of Micromechanics and Microengineering*, **2005**, 15, 1027-1032	2	1
29	Experimental analysis of the effect of metal thickness on the quality factor in integrated spiral inductors for RF ICs. *IEEE Electron Device Letters*, **2004**, 25, 76-79	4.4	47
28	Shape-controlled, high fill-factor microlens arrays fabricated by a 3D diffuser lithography and plastic replication method. *Optics Express*, **2004**, 12, 6366-71	3.3	82
27	3-D construction of monolithic passive components for RF and microwave ICs using thick-metal surface micromachining technology. *IEEE Transactions on Microwave Theory and Techniques*, **2003**, 51, 279-288	4.1	69
26	A new monolithic microbiosensor for whole blood analysis. *Sensors and Actuators A: Physical*, **2002**, 95, 108-113	3.9	10
25	CMOS-compatible surface-micromachined suspended-spiral inductors for multi-GHz silicon RF ICs. *IEEE Electron Device Letters*, **2002**, 23, 591-593	4.4	89
24	Fabrication of polymeric large-core waveguides for optical interconnects using a rubber molding process. *IEEE Photonics Technology Letters*, **2000**, 12, 62-64	2.2	32
23	A high fill-factor infrared bolometer using micromachined multilevel electrothermal structures. *IEEE Transactions on Electron Devices*, **1999**, 46, 1489-1491	2.9	35

22	Monolithic integration of 3-D electroplated microstructures with unlimited number of levels using planarization with a sacrificial metallic mold (PSMM) **1999**,		5
21	A thermal inkjet printhead with a monolithically fabricated nozzle plate and self-aligned ink feed hole. *Journal of Microelectromechanical Systems*, **1999**, 8, 229-236	2.5	40
20	Surface micromachined solenoid on-Si and on-glass inductors for RF applications. *IEEE Electron Device Letters*, **1999**, 20, 487-489	4.4	81
19	Monolithic Fabrication of Electroplated Solenoid Inductors Using Three-Dimensional Photolithography of a Thick Photoresist. *Japanese Journal of Applied Physics*, **1998**, 37, 7081-7085	1.4	36
18	Hermetically Sealed Inductor-Capacitor (LC) Resonator for Remote Pressure Monitoring. *Japanese Journal of Applied Physics*, **1998**, 37, 7124-7128	1.4	47
17	Multilevel microstructure fabrication using single-step 3D photolithography and single-step electroplating **1998**,		11
16	Fabrication of a Single Crystal Silicon Substrate for AM-LCD Using Vertical Etching of (110) Silicon. *Materials Research Society Symposia Proceedings*, **1995**, 377, 859		2
15	A New Three-Dimensional Lithography Using Polymer Dispersed Liquid Crystal (PDLC) Films		1
14	Micromachined CPW-fed suspended patch antenna for 77 GHz automotive radar applications		1
13	3D diffuser lithography: a novel method to fabricate various rounded microstructures		1
12	Performance comparison of 5GHz VCOs integrated by CMOS compatible high Q MEMS inductors		2
11	A low loss MEMS transmission line with shielded ground		4
10	High fill-factor micromirror array and its fabrication process		1
9	A low-voltage two-axis electromagnetically actuated micromirror with bulk silicon mirror plates and torsion bars		2
8	A high-performance MEMS transformer for silicon RF ICS		2
7	3-D lithography and metal surface micromachining for RF and microwave MEMS		7
6	Electrostatic digital micromirror using interdigitated cantilevers		3
5	A disposable DNA sample preparation microfluidic chip for nucleic acid probe assay		1

4	High-performance electroplated solenoid-type integrated inductor (SI/sup 2/) for RF applications using simple 3D surface micromachining technology	9
3	Monolithic high-Q overhang inductors fabricated on silicon and glass substrates	21
2	High-performance three-dimensional on-chip inductors fabricated by novel micromachining technology for RF MMIC	6
1	A surface-micromachined tunable microgyroscope	2